

ABSTRACT OF THE DISCLOSURE

A method for inspecting a thin film transistor active matrix substrate comprises a step for opposing a probe to the substrate, a step for supplying a dielectric fluid between the substrate and the probe, a step for supplying power to a closed circuit containing the substrate and the probe, and a step for sensing a signal passed through the closed circuit by the power supply. Using this method, a non-contact TFT array substrate inspection apparatus with high throughput, which is also suitable for organic EL substrates, can be realized.

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